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500.40120X00

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): T. OTSUBO, et al  
Serial No.: 09/855,674  
Filed: May 16, 2001  
For: APPARATUS FOR MONITORING THICKNESS OF  
DEPOSITED LAYER IN REACTOR AND DRY PROCESSING  
METHOD  
Group: 2877  
Examiner: K. Brown

**AMENDMENT**

Mail Stop Non-Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 22, 2003

Sir:

In response to the Office Action dated June 19, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendments to the Claims;

Remarks are included following the amendments; and

An Appendix including amended drawing figures is attached following the Remarks.

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